

A B S T R A C T

A plasma treatment apparatus comprises: an airtight treatment chamber; a lower electrode including a mount portion on which an object is to be mounted, 5 the lower electrode being movable up and down in the treatment chamber; a power supply system to supply high-frequency power to the lower electrode; an elevator mechanism to move the lower electrode up and down; a conductive wall body substantially surrounding 10 the elevator mechanism in close proximity and forming a path reaching to a floor portion of the treatment chamber; and a conductive member provided around the lower electrode and electrically connecting an inner wall of the treatment chamber and the wall body.